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# U.S. UTILITY Patent Application

AK 103  
SCANNED

**PATENT DATE**

APPLICATION NO. 09/805188	CONT/PRIOR D F	CLASS 356	SUBCLASS 237.5	ART UNIT 2877	EXAMINER Nguyen, T
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**TITLE** **APPLICANTS**

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Method and apparatus for analyzing the state of generation of foreign particles in semiconductor fabrication process

PTO-2040  
12/99

# ISSUING CLASSIFICATION

[illegible]

<input type="checkbox"/> <b>TERMINAL DISCLAIMER</b>	<b>DRAWINGS</b>			<b>CLAIMS ALLOWED</b>	
	Sheets Drwg.	Figs. Drwg.	Print Fig.	Total Claims	Print Claim for O.G.
<input type="checkbox"/> The term of this patent subsequent to _____ (date) has been disclaimed.	_____ (Assistant Examiner) _____ (Date)			<b>NOTICE OF ALLOWANCE MAILED</b>	
<input type="checkbox"/> The term of this patent shall not extend beyond the expiration date of U.S. Patent No. _____ _____ _____	_____ (Primary Examiner) _____ (Date)			<b>ISSUE FEE</b>	
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